

## CLAIM AMENDMENTS

Please amend the claims as follows.

1. (Previously presented) An apparatus for measuring surface topography of a surface comprising:

a linearly polarized light source that generates a light beam;

optics that focus the light beam on a surface to be measured such that a normally incident beam deflection is provided, the optics including polarization optics such that the incident beam has a first polarization and a reflected beam from the surface has a second polarization different from the first polarization, the optics including: a half-wave plate that receives the light beam from the linearly polarized light source; a long working distance microscope objective positioned to receive the light beam as an input from the half-wave plate and output a converging light beam; and a polarizing beam splitter positioned to receive as an input the output of the half-wave plate and produce as an output a light beam with the first polarization; and

a position sensitive detector positioned to detect the reflected beam.

2. (canceled).

3. (canceled).

4. (canceled).

5. (Previously presented) The apparatus of claim 1, wherein the optics further include a quarter-wave plate positioned to receive as an input the light beam with the first polarization and output a beam in a direction normally incident to the surface, the reflected beam from the surface being reflected by the quarter-wave plate towards the position sensitive detector.

6. (Original) The apparatus of claim 5, wherein the first polarization is a p-polarization and the second polarization is s-polarization.

7. (Original) The apparatus of claim 6, wherein the polarizing beam splitter includes a  $45^\circ$  reflective surface positioned to reflect the beam reflected from the surface in a direction perpendicular to the direction normally incident to the surface.

8. (Previously presented) The apparatus of claim 1 wherein the long working microscope objective outputs the converging light beam in a direction perpendicular to a normally incident direction to the surface.

9. (Original) The apparatus of claim 8, wherein the optics further include a polarizing beam splitter having a  $45^\circ$  reflective surface positioned to reflect the converging light beam from the long working microscope objective towards the surface in a normally incident direction to the surface.

10. (Original) The apparatus of claim 9, wherein the optics further include a quarter-wave plate positioned to receive as an input the light beam with the first polarization from the polarizing beam splitter and output a beam that is normally incident to the surface, with a reflected beam from the surface having the second polarization and directed by the quarter-wave plate through the polarizing beam splitter in a direction normal to the surface towards the position sensitive detector.

11. (Previously presented) A method of measuring the topography of a surface, comprising the steps of:

directing a beam of light of a first polarization towards a surface to be measured, the beam of light being directed at the surface in a direction normally incident to the surface, with a reflected beam from the surface also being normally incident to the surface, with a

reflected beam from the surface also being normally incident to the surface, the directing including: generating a collimated beam of linearly polarized light and passing the collimated beam through a half-wave plate; converging the collimated beam with a long working distance microscope objective to output a converging beam; and transmitting the converging beam through a polarizing beam splitter in a direction normally incident to the surface;

changing the polarization of the reflected beam to a second polarization different from the first polarization;

directing the reflected beam with the second polarization to a position sensitive detector; and

determining the topography from measurement taken at the position sensitive detector.

12. (canceled).

13. (canceled).

14. (canceled).

15. (Previously presented) The method of claim 11, wherein the step of changing the polarization includes passing the reflected beam through a quarter-wave plate that changes the polarization of the reflected beam to the second polarization from the first polarization.

16. (Original) The method of claim 15, wherein the step of directing the reflected beam includes reflecting the reflected beam perpendicularly at the polarizing beam splitter towards the position sensitive detector.

17. (Previously presented) The method of claim 11, wherein the step of directing a beam of light includes directing the converging beam in a direction perpendicular to a normally

incident direction to the surface towards a reflective surface of a polarizing beam splitter that reflects the converging beam towards the surface in a direction normally incident to the surface.

18. (Original) The method of claim 17, wherein the step of directing the reflected beam includes transmitting the reflected beam through the polarizing beam splitter in a normal direction to the surface towards the position sensitive detector.

19. (canceled).

20. (canceled).

21. (New) An apparatus for measuring surface topography of a surface comprising:  
a linearly polarized light source that generates a light beam;  
optics that focus the light beam on a surface to be measured such that a normally incident beam deflection is provided, the optics including polarization optics such that the incident beam has a first polarization and a reflected beam from the surface has a second polarization different from the first polarization, the optics including: a half-wave plate that receives the light beam from the linearly polarized light source; a long working distance microscope objective positioned to receive the light beam as an input from the half-wave plate and output a converging light beam; and a polarizing beam splitter positioned to receive as an input the output of the half-wave plate and produce as an output a light beam with the first polarization; and  
a position sensitive detector positioned to detect the reflected beam;  
wherein the optics further include a polarizing beams splitter having a 45° reflective surface positioned to reflect the converging light beam from the long working microscope objective towards the surface in a normally incident direction to the surface.

22. (New) ) The apparatus of claim 21, wherein the optics further include a quarter-wave plate positioned to receive as an input the light beam with the first polarization from the polarizing beam splitter and output a beam that is normally incident of the surface, with a reflected beam from the surface having the second polarization and directed by the quarter-wave plate through the polarizing beam splitter in a direction normal to the surface towards the position sensitive detector.